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**AMENDMENTS TO THE CLAIMS:** 

1. (Currently Amended) A remote control system for one or more semiconductor

manufacturing apparatuses capable of accessing comprising:

a supervisory device [[of]] which controls said one or more semiconductor

manufacturing apparatuses from apparatuses; and

a remote operation device that accesses said supervisory device through a

communication line,

wherein upon accessing said supervisory device, said remote operation device

simultaneously displays the same screen as that displayed [[in the]] by said supervisory

device, and enables said remote operation device to perform the same operations as those

carried out by said supervisory device to be performed on said one or more semiconductor

manufacturing apparatuses.

2. (Currently Amended) The remote control system for one or more semiconductor

manufacturing apparatuses according to claim 1, wherein said supervisory device performs

user authentication when said remote operation device is connected connects to said

supervisory device.

3. (Currently Amended) A semiconductor manufacturing apparatus connected to said

supervisory device accessible to said remote operation device. The remote control system for

one or more semiconductor manufacturing apparatuses according to claim [[1]] 1, wherein

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upon accessing said supervisory device, said remote operation device simultaneously displays

the same screen as that displayed in the said supervisory device.

4. (Currently Amended) A remote operation device for use with said The remote control

system for one or more semiconductor manufacturing apparatuses according to claim [[1]] 1,

wherein said supervisory device includes an IP routing function for achieving remote control

operation from said remote operation device.

5. (Currently Amended) A remote control system for one or more semiconductor

manufacturing apparatuses comprising:

a local area network system including a host device operably connected to said [[and]]

one or more semiconductor manufacturing apparatuses; and

a remote operation device [[with]] including a communication element accessible to

that accesses said host device on the semiconductor manufacturing side by way of a

communication line;

wherein said host device is provided with an IP routing function and protocols

necessary for achieving remote control operation from said remote operation device, and a

communication element having a call incoming function [[of]] for receiving a call incoming

from said communication line, and

said host device serves to perform performs user authentication when said remote

operation device tries to connects to said host device, so that wherein upon

authentication said remote operation device thus authenticated can display simultaneously

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displays the same screen as that displayed on said host device, permitting said remote

operation device to remotely control and operate said host device.

6. (Currently Amended) The remote control system for one or more semiconductor

manufacturing apparatuses according to claim 5, wherein said host device and said remote

operation device each have a modem as said communication element for enabling connection

between said host device and said remote operation device through one of an analog line

[[or]] and an analog network.

7. (Currently Amended) The remote control system for one or more semiconductor

manufacturing apparatuses according to claim 5, wherein said host device and said remote

operation device each have a terminal adapter as said communication element for enabling

connection between said host device and said remote operation device through one of an

ISDN line [[or]] and a network.

8. (Currently Amended) A remote control system for one or more semiconductor

manufacturing apparatuses comprising:

a local area network system including comprising a plurality of host devices each

connected with one or more semiconductor manufacturing apparatuses, and a router as its

eommunication element connected with said host devices; and

a remote operation device [[with]] including a router as its communication element

accessible to that accesses said host devices on the semiconductor manufacturing apparatus

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side by way of a communication line;

wherein said host devices are each provided with an IP routing function and protocols necessary for achieving remote control operation from said remote operation device, and a communication element having a call incoming function [[of]] for receiving a call incoming from said communication line, and

said host devices each serve to perform user authentication when said remote operation device tries to connect connects to said host devices, so that said remote operation device thus authenticated can individually simultaneously display the same screen as that displayed on each of said host devices, permitting said remote operation device to remotely control and operate said host devices.

- 9. (Original) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises the Internet.
- 10. (Currently Amended) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises one of a local area network [[or]] and a wide area network.
- 11. (Currently Amended) A remote control system for one or more semiconductor manufacturing apparatuses comprising:

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a local area network system including comprising a plurality of host devices each connected with one or more at least one semiconductor manufacturing apparatuses apparatus, and an access server as its communication element connected with said host devices; and

a plurality of remote operation devices with a plurality of each having a communication elements, respectively, element accessible to said host devices on the semiconductor manufacturing apparatus side by way of a plurality of communication networks network:

wherein said host devices are each provided with an IP routing function and protocols necessary for achieving remote control operation from each of said remote operation devices, and

said host devices each serve to perform user authentication when each of said remote operation devices tries to connects to said host devices, so that wherein each of said remote operation devices thus authenticated can individually simultaneously display the same screen as that displayed on each of said host devices, permitting said remote operation devices to remotely control and operate said host devices.

12. (Currently Amended) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, wherein said plurality of communication networks network connecting between said host devices and said remote operation devices include comprises at least one of a public telephone network, an ISDN network, the Internet, a local area network and a wide area network.

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13. (New) The remote control system for one or more semiconductor manufacturing

apparatuses according to claim 5, wherein said remote operation device enables same

operations as those carried out by said host device.

(New) The remote control system for one or more semiconductor manufacturing 14.

apparatuses according to claim 8, wherein said remote operation device enables same

operations as those carried out by said host devices.

15. (New) The remote control system for one or more semiconductor manufacturing

apparatuses according to claim 11, wherein each of said remote operation devices enables

same operations as those carried out by said host devices.